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THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Applicant:

Michael L. McSwiney et al.

Serial No.: 10/764,193

Filed: January 23, 2004

For: Forming a Silicon
Nitride Film

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Art Unit: 1792

Examiner: David P. Turocy

Atty Docket: ITL.1056US
P17793

Assignee: Intel Corporation

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

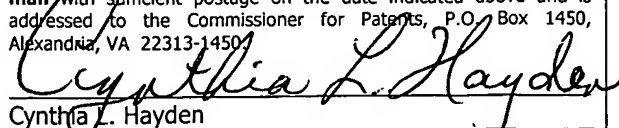
REPLY TO OFFICE ACTION

Sir:

In response to the office action mailed March 17, 2008, please amend the above-referenced patent application as follows:

Date of Deposit: June 5, 2008

I hereby certify under 37 CFR 1.8(a) that this correspondence is being deposited with the United States Postal Service as **first class mail** with sufficient postage on the date indicated above and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.


Cynthia L. Hayden